



PATENT  
Atty. Dkt. AMAT/2592.C9/DSM/LOW K/JW

IFW

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of:  
Gaillard, et al.

Serial No.: 10/789,209

Filed: February 27, 2004

Confirmation No.: Unknown

For: Method of Decreasing the  
K Value in SIOC Layer  
Deposited by Chemical  
Vapor Deposition

MAIL STOP AMENDMENT  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

<b>CERTIFICATE OF MAILING</b> <b>37 CFR 1.8</b>
<p>I hereby certify that this correspondence is being deposited on  <u>5/19</u>, 2004 with the United States Postal Service as          First Class Mail in an envelope addressed to: Mail Stop          Amendment, Commissioner for Patents, P.O. Box 1450          Alexandria, VA 22313-1450.</p>
<u>5/19/04</u> <u>Kent L. Zurb</u> Date                  Signature

## **PRELIMINARY AMENDMENT**

Prior to examination, please amend the above-identified application as shown below. **Amendments to the Specification** begin on page 2. **The Pending Claims** begin on page 3. **Remarks** begin on page 7.